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CONTENTS

pages 349-380

9th AUGUST 1973 Vol. 9 No. 16

CIRCUIT DESIGN	page
Continuously equivalent networks in state space R. Devanathan (India)	372
Generating function for spanning trees	360
B. R. Myers (USA)	270
S. Tirtoprodjo (<i>Netherlands</i>)	570
Realisation of colmers and rowmers Y. Ceyhun and S. Penbeci (<i>Turkey</i>)	364
COMPUTERS & LOGIC	
Synthesis of outpoint cellular arrays with any cell-index set	350
Large-matrix-ordering technique with applications to transposition	374
De Lotto and D. Dotti (<i>Italy</i>) Effects of binary quantisation when using the fast Fourier transform to compute powerspectral estimates	361
J. D. S. Mason (UK)	
ELECTROMAGNETICS	
Use of dither to eliminate hysteresis effects in rotating amplifiers P. L. Simpson and H. M. Power (IIK)	369
Power-frequency distribution in a cavity containing a resonant ferrite sample	357
W, J. R. Hoefer (<i>Canada</i>)	
<u>ELECTRO-OPTICS</u>	
1-arm phase optical bridge with axial symmetry [with interference Newton fringes] for measuring small periodic displacements	355
M. I. Borisov and J. I. <u>Burov (<i>Bulgaria</i>)</u>	555
MATERIALS & SEMICONDUCTOR DEVICES	
Analytic theory for silicon double-sided n'-n-p-p TRAPATT-diode structures M. G. Cottam (IIK)	353
Pulsed measurement of transistor-base charge against collector current R Bridgen (<i>IIK</i>)	366
Multiplication factors and breakdown voltages of n' p and $p*n$ abrupt junctions	367
P. Spirito (<i>Italy</i>) Reply to comment on metal-nitride-oxide -silicon avalanche-injection memory	349
J. Mavor (UK) Estimate of substrate influence on space-charge-limited current	351
E. De Chambost(France)	255
Correlation of noise current and voltage in transistor—base regions H.Sutdiffe (UK)	3/5
Metal-insulator-semiconductor electroluminescent diodes in single-crystal zinc oxide B. W. Thomas and D. Walsh (UK)	362
Experimental verification of the Shockley-Read-Hall recombination theory in silicon W. Zimmerman (Switzerland)	378
MICROWAVE TECHNIQUES & RADAR	
Characteristic impedance of surface-strip coplanar waveguides	354
P. A. J. Dupuis and C. K. Campbel] (<i>Canada</i>) Low attenuation in corrugated circular waveguides	376
P. J. B. Clarricoats and A. D. Olver (UK)	
SURFACE ACOUSTIC WAVES	
Convolution and imaging in acoustic-surface-wave thin-film guides R = A - Zakarevicius = E - A - Ash and L M - Mason (UK)	363
EVETENCE CONTROL ENCINEEDINC	
Decoupling and pole assignment in nonlinear systems	373
E. Freund (USA) Structural modification of dvadic transfer function matrices using feedback	270
D. H. Owens (UK)	517
Signal-flowgraph analysis using only loops U. Orguner (USA)	359
Errata	380

THE INSTITUTION OF ELECTRICAL ENGINEERING

1-ARM PHASE OPTICAL BRIDGE WITH AXIAL SYMMETRY (WITH INTERFERENCE NEWTON FRINGES) FOR MEASURING SMALL PERIODIC DISPLACEMENTS

Indexing terms: Displacement measurement. Bridge instruments, Vibration measurement. Optical modulation, Phase modulation

A 1-arm phase optical bridge with axial symmetry (with interference Newton fringes) is developed for the measurement of small periodic displacements of acoustic frequency. Using the synchronous detection method, a vibration with an amplitude as small as 3×10^{-14} m is measured.

Various optical methods have been used for the noncontact measurement of small periodic displacements (1-6). In these, the vibrating object changes (modulates) the direction of propagation, the polarization, the phase of the frequency of an electromagnetic wave.

The phase-bridge method is distinguished by high sensitivity, high precision, and by a wide range of measurable periodic displacements. In it, the vibrating object modulates the phase of a monochromatic light beam. The latter interferes with another coherent monochromatic beam with a constant phase. The measurement of the phase modulation, respecting the amplitude of the vibration, is reduced to the measurement of a variable luminous flux.

In the measurement of small periodic displacements, 2arm phase bridges of the type of the Michelson interferometer are most often used. In some works, the semitrans parent mirror of the Michelson interferometer is replaced by a Bragg cell to secure an additional amplitude modulation of the two interfering light beams.^{3,4}

Compared with 2-arm optical phase bridges, the use of an 1-arm phase optical bridge with axial symmetry offers certain



Fig. 1 Equipment

advantages: the construction of the interferometer is substantially simplified, which secures an easy adjustment, and makes it possible to produce easily loworder interference; the intensity of the light beam is most fully used; the noise from the mechanical vibrations is strongly reduced, because the interferometer has only one short arm (one usually works with low-order interference).

Fig. 1 is a block-diagram of the equipment used for measuring small periodic displacements. The surface of the vibrating plate 1 (the vibrations of which are to be measured), and the convex surface of the planoconvex lens 2 with a small radius of curvature R, enclose an air layer. The latter is illuminated with monochromatic light from an He-Ne laser (light wavelengths $\mathbf{l} = 6.328 \times 10^{-7}$ m).

The luminous flux $\mathbf{f}(r)$ incident on the cathode of the photomultiplier as a function of the radius r of the blend 3 is

$$\Phi(r) = \Phi_{\sim}(r) \cos \frac{\mathbf{p}}{\mathbf{l}} \left(\frac{r^2}{R} + 4d - \mathbf{l}\right) \sin \frac{\mathbf{p}r^2}{\mathbf{l}R} + \Phi_{=}(r)$$
$$\Phi_{=}(r) = I_0 \mathbf{p}r^2 \qquad \Phi_{\sim}(r) = I_0 R \mathbf{l} \qquad (1)$$

provided that the two light beams reflected from the surfaces enclosing the air layer have the same intensity I_0 , d being the layer thickness. The maximum modulation of the luminous flux, with respect to the current across the photomultiplier, i.e. maximal $\left|\partial f/\partial d\right|$ when d is varied, is obtained under the following conditions

$$d_0 = (n+1)I/4$$
 $r_0 = \sqrt{\frac{IR}{2}}$ (2)

n being the order of the interference maximum at the central fringe. From eqn. 1 for the luminous flux incident on the photomultiplier cathode at $\mathbf{r}^2 = \mathbf{I} R/2$, one obtains, substituting u, u_{\pm} and u_{\sim} the voltage across the load resistance of the photomultiplier for $\Phi(r)$, $\Phi_{\pm}(r)$ and $\Phi_{\sim}(r)$,

$$u = u_{\pm} + u_{\sim} \sin \frac{4p}{l} d \tag{3}$$

the u_s being proportional to the Φ_s as a result of the linearity of the lux illuminance/current ampere characteristic of the photomultiplier.

When plate 1 is displaced at a distance 1/4, the central interference maximum [at $d_0 = (n+1/4)1/2$] is replaced by its neighbouring minimum [at $d_0 = (n+3/4)$]/2]; consequently, the voltage across changes from a maximum value $u_{max} = u_{=} + u_{\sim}$ to a minimum value $u_{min} = u_{=} - u_{\sim}$. Hence, it follows that

$$u_{\sim} = \frac{u_{\max} - u_{\min}}{2} \tag{4}$$

Now, if plate 1 vibrates according to the sine law $d = d_0 + d \sin Wt$ ($d \langle \langle \mathbf{I} \rangle$), an alternating voltage of the same frequency and with an effective value

 Δu_{ev} results across R_{T} . From eqn. 3, using eqn. 4, one obtains

$$d' = \frac{\sqrt{2}}{2} \frac{l}{p} \frac{\Delta u_{ev}}{u_{\max} - u_{\min}}$$
(5)

provided that the conditions of eqns. 2 are observed.

The use of eqn. 5 in computing the amplitude of the vibration requires that the distance d_0 between the plate and the lens be preliminarily so adjusted that the luminous flux incident on the photomultiplier cathode be $(f_{\text{max}} + f_{\text{min}})/2$; i.e. that the voltage across R_T be $(u_{\text{max}} + u_{\text{min}})/2$.

The sensitivity of the method, i.e. the lowest amplitude that can be measured, is limited by the shot-noise level of the photomultiplier as well as by the indeterminacy principle.^{7, 8} The shot noise of the photomultiplier hinders the measurement of amplitudes lower than $d_{\min}^{"}$, determined by the inequality

$$d_{\min}^{"} \geq \frac{1}{4pr_0^2 g} \sqrt{\frac{e\Delta f}{aI_0}} = \frac{1}{p(u_{\max} - u_{\min})} \sqrt{eu_0\Delta fR_T}$$
(6)

where Δf is the bandwidth of the electronic equipment following the photomultiplier, e is the electronic charge, $g = \sin(\Delta W/c)d/(\Delta W/c)d$ is the factor of monochromatism, c is the velocity of light, a is the sensitivity of the photomultiplier and $u_0 = (u_{\max} + u_{\min})/2$ is the voltage across R_T when the vibrating plate is at its equilibrium position. Eqn. 6 is obtained by equating the average value of the voltage amplitude

$$\overline{\Delta u^{2}} = \frac{(\Delta u)^{2}}{2} = \frac{\left\{ (\sqrt{2}) \Delta u_{ev} \right\}^{2}}{2} = (\Delta u_{ev})^{2} =$$
$$= 2 \frac{d''_{min}}{l^{2}} p^{2} (u_{max} - u_{min})^{2}$$

to the average value of the photomultiplier noises, $u^2 = 2eu_0\Delta fR_T$ passing through the equipment. According to the indeterminacy principle, the size pr^2 of the light spot on the vibrating surface determines, in principle, the lowest possible amplitude d^{min} of the vibration that can

be measured by means of the inequality

$$d^{'''}_{\min} \ge \frac{m\mathbf{I}^2}{8\mathbf{p}r^2} \tag{7}$$

where m is the order of the interference maximum.

On using synchronous detection at a frequency of vibration of the plate 991 Hz, $\Delta f = 0.01$ Hz, $u_{\text{max}} = 24$ V, $u_{\text{min}} = 9$ V, $R_T = 47$ kW, the smallest vibration that can safely be measured corresponds to a voltage of the order of $d' = 3 \times 10^{-6}$ V (Fig. 2). This corresponds to a vibration amplitude $d' = 3 \times 10^{-14}$ m. The latter amplitude is one order of magnitude higher than the lowest amplitude, measurable under the conditions of the experiment



Fig. 2 Frequency of vibration

Vertical scale: 1 -5 x 10^{-7} V /division Horizontal scale: 2 min /division

 $(m=2, r=3\times10^{-3} m)$ in accordance with the indeterminacy principle (expr. 7) at the given noise of the electronic equipment (eqn. 6).

The equipment as described was used to measure vibrations of acoustic frequency (up to 10^4 Hz). It can be employed for measuring the electrostriction. magnetostriction and piezoelectric coefficients of various materials, as well as for investigating phase transitions in ferroelectrics and ferromagnetics. On cooling, a considerable enhancement of the sensitivity by 1-2 orders of magnitude can be expected, owing to the reduction of the shot noise of the photomultiplier, Such an enhancement may be important for the problem of detecting gravitational waves.^{8, 9} The use of the abovedescribed equipment in the measurement of small vibrations

of high frequency Ω_1 (e.g. in the case of surface waves) is possible by modulating the intensity of the laser beam with a frequency Ω_2 close to Ω_1 and measuring the amplitude of the photomultiplier signal at a frequency $\Omega_2 - \Omega_1$.

29th June 1973 M. I. BORISOV

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References

- 1 BERNSTAIN, I. L.: 'Measurements of very small changes of optical path differences of two light waves'. *Sov. Phys.-Dan SSSR*, 1954, 94, pp. 655-658
- 2 SAUERBREY, G.: 'Messung von Plattenschwingungen sehr kleiner Amplitude durch Licbslrommodulation', Z. Phys; 1964, 178, pp. 457-471

- 3 ASH, E., DE LA RUE, and HUMPRYES, R.: 'Microsound surface waveguides', *IEEE Trails.*. 1969, MTT-17, pp. 882-892
- 4 WHITMAN, R., LAUB, L., and BATES, W.: 'Acoustic surface displacement measurements on a wedgeshaped transducer using an optical probe technique', *ibid.*, 1968, SU-15, pp. 186-189
- 5 VYCE, R.: 'An optical, noncontacting surface sensor (optical probe)', *Appl. Opt.*, 1969, 8, pp. 2301-2310
- 6 AUTH, D., and MAYER, W.: 'Scattering of light reflected from acoustic surface waves in isotropic solids', J. Appl. Phys., 1967, 38, pp. 5138-5140
- 7 KOPPELMAN, G.: 'Eine beugungsbedingte Auflosungsgrenze in der Mehrstrahl-Iirterferometric', *Opt. Acta*, 1966, 13, pp. 211-227
- 8 KARTASHEV, A,, and ETSIN, I.: 'Methods of measurement of small changes of phase difference in the interference arrangements', *SOV. Phys.-Usp.*, 1972, 106, pp. 687-72)
- 9 WEBER. J.: 'Gravitational waves', *Phys. Today*, 1968, 21, pp. 34-39